



PATENT
2557-000177/US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANTS: Chang Won CHOI et al. CONF. NO.: 5346
SERIAL NO.: 10/762,526 GROUP: 1763
FILED: January 23, 2004 EXAMINER: Lund, J.R.
FOR: WAFER EDGE ETCHING APPARATUS AND METHOD

**AMENDMENT FILED CONCURRENTLY WITH
REQUEST FOR CONTINUED EXAMINATION (RCE)**

September 4, 2007

Customer Service Window
Randolph Building
401 Dulany Street
Alexandria, VA 22314
Mail Stop RCE

Dear Sir:

Responsive to the Official Action dated May 3, 2007, and concurrent with the filing of an RCE, the following amendments and remarks are respectfully submitted in connection with the above-referenced application.

Amendments to the claims begin on page 2 of this paper.

Remarks begin on page 11 of this paper.

	Claims remaining after Amendment		Highest number previously paid for		Present extra
Total	44	-	44	=	0
Independent	6	-	6	=	0